

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: TAKASHI HAGINO ET AL.)
SERIAL NO.: 10/080,424) Group Art Unit:
FILED: February 22, 2002) 2823
FOR: METHOD FOR MANUFACTURING)
POLYCRYSTALLINE SEMICONDUCTOR)
LAYERS AND THIN-FILM TRANSISTORS,)
AND LASER ANNEALING APPARATUS)
Examiner:
W. D. Coleman

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AMENDMENT

OFFICIAL

Via Facsimile to 703-872-9306
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed July 11, 2003, Applicants request reconsideration in the view of the following amendment and remarks for entry in the above-identified application.

I hereby certify that this correspondence was facsimile transmitted to the United States Patent Office (Fax No. 703-872-9306) on	
January 9, 2004	
(Date of Deposit)	
Patricia A. Uari	
(Name of Person Mailing Paper)	
<i>Patricia A. Uari</i>	01/09/04
Signature	Date